

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re application of	)	ATOMIC LAYER DEPOSITION
	)	METHOD AND SEMICONDUCTOR
Hwang et al.	)	DEVICE FABRICATING
	)	APPARATUS HAVING ROTATABLE
Application No.	)	GAS INJECTORS
	)	Group Art Unit:
Filing Date:	)	
		Examiner:

Commissioner for Patents  
P.O. Box 1450  
Mail Stop: Divisional Patent Application  
Alexandria, VA 22313-1450

**PRELIMINARY AMENDMENT**

Dear Sir:

Applicant hereby submits the following Preliminary Amendment to the above-referenced application.

Amendments to the Specification begin on page 2 of this paper.

Amendments to the Claims are reflected in the listing of claims which begins on page 3 of this paper.

Remarks begin on page 5 of this paper.